

ION MILL SHUTTER SYSTEM

Abstract of the Disclosure

5 A method for producing magneto resistive heads includes the steps of
positioning at least two magneto resistive elements in spaced relation to one another
and placing the at least two magneto resistive elements in an ion milling
environment where material is removed nonselectively from items in the
environment. A property of at least two of the plurality of magneto resistive
elements is monitored. In response to monitoring, one of the at least two magneto
10 resistive elements is dynamically covered to prevent additional removal of material
from the covered magneto resistive element.

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